Physics-Guided Optimisation of Thermosonic Gold Stud Bump Bonding on Glass for a TPT-HB16 Wire Bonder

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TABLE I Symbols

$egin{array}{ll} D_w & ext{Wire diameter} \ D_{ ext{FAB}} & ext{Free-air-ball diameter} \ F & ext{Applied normal force} \ P_{ ext{US}} & ext{Ultrasonic power at capillary} \ t & ext{Duration of ultrasonic vibration} \ E & ext{Ultrasonic energy } (P_{ ext{US}}t) \ T & ext{Substrate temperature} \ \end{array}$		
$\begin{array}{lll} D_{\mathrm{FAB}} & \mathrm{Free\text{-}air\text{-}ball\ diameter} \\ F & \mathrm{Applied\ normal\ force} \\ P_{\mathrm{US}} & \mathrm{Ultrasonic\ power\ at\ capillary} \\ t & \mathrm{Duration\ of\ ultrasonic\ vibration} \\ E & \mathrm{Ultrasonic\ energy\ }(P_{\mathrm{US}}t) \\ T & \mathrm{Substrate\ temperature} \\ \sigma_y & \mathrm{Yield\ strength\ of\ gold\ at\ }T \end{array}$	Symbol	Definition
$ \begin{array}{lll} F & & \text{Applied normal force} \\ P_{\text{US}} & & \text{Ultrasonic power at capillary} \\ t & & \text{Duration of ultrasonic vibration} \\ E & & \text{Ultrasonic energy} \ (P_{\text{US}}t) \\ T & & \text{Substrate temperature} \\ \sigma_y & & \text{Yield strength of gold at} \ T \\ \end{array} $	$\overline{D_w}$	Wire diameter
$P_{ ext{US}}$ Ultrasonic power at capillary t Duration of ultrasonic vibration E Ultrasonic energy $(P_{ ext{US}}t)$ Substrate temperature σ_y Yield strength of gold at T	$D_{\rm FAB}$	Free-air-ball diameter
$ \begin{array}{ll} t & \text{Duration of ultrasonic vibration} \\ E & \text{Ultrasonic energy } (P_{\text{US}}t) \\ T & \text{Substrate temperature} \\ \sigma_y & \text{Yield strength of gold at } T \end{array} $	F	Applied normal force
$ \begin{array}{ll} t & \text{Duration of ultrasonic vibration} \\ E & \text{Ultrasonic energy } (P_{\text{US}}t) \\ T & \text{Substrate temperature} \\ \sigma_y & \text{Yield strength of gold at } T \end{array} $	P_{US}	Ultrasonic power at capillary
T Substrate temperature σ_y Yield strength of gold at T	t	
σ_y Yield strength of gold at T	E	Ultrasonic energy $(P_{US}t)$
	T	Substrate temperature
	σ_y	Yield strength of gold at T
	$\check{D_m}$	Final bump diameter

Abstract—We present a quantitative recipe for fabricating near-spherical gold stud bumps with 25 μm wire on Ti (50 nm)Au (100 nm) electrodes on 1 mm glass. Analytical models link ultrasonic energy, normal force and temperature to gold yield strength and interfacial slip. Closed-form expressions provide minimum bond force, optimum ultrasonic energy and bump deformation, all validated against literature. Applied to a TPT-HB16, ultrasonic time was reduced from 250 ms to 50 ms while achieving more than 120 gf shear strength and $\pm 2\,\mu m$ diameter spread.

Index Terms—Gold stud bump, thermosonic bonding, process optimisation, ultrasonic energy, yield strength model

I. INTRODUCTION

Gold stud bump (GSB) bonding enables single-step flip-chip interconnects on diverse substrates [1], [2]. However, the interplay of ultrasonic power, bonding force and temperature must be balanced to avoid under-bonding or over-mashing. We derive explicit scaling laws and apply them to optimise the TPT HB16 profile for $25\,\mu m$ wire.

II. PROCESS THEORY AND GOVERNING EQUATIONS

Key symbols are summarised in Table I.

A. Temperature-Dependent Yield Strength

The yield strength follows an exponential decay with temperature [6]:

$$\sigma_y(T) = \sigma_0 \exp[-\beta (T - T_0)],$$
 (1)

with $\sigma_0 = 220 \,\text{MPa}$ at $T_0 = 25 \,^{\circ}\text{C}$ and $\beta = 0.010 \,\text{K}^{-1}$.

B. Minimum Force for Plastic Flattening

Assuming Hertzian contact between a hemispherical FAB and the pad [5], the minimum force is

$$F_{\min} = k \,\sigma_y(T) \,D_w^2,\tag{2}$$

where $k = \pi/4$.

C. Interfacial Slip and Bonded Area

The bonded area fraction η depends on frictional work [3]:

$$\eta = 1 - \exp[-\gamma F E],\tag{3}$$

with $\gamma=4.2\times 10^{-4}\,{\rm mJ^{-1}N^{-1}}$ for 25 µm wire [4]. Full bonding ($\eta\ge 0.98$) requires

$$E_{\min} = \frac{-\ln(0.02)}{\gamma F}.\tag{4}$$

D. Bump Deformation

Excess force or energy enlarges the mashed diameter [6]:

$$D_m = D_{\text{FAB}} [1 + \alpha (F/E)], \tag{5}$$

where $\alpha = 0.18 \,\mathrm{mJ}\,\mathrm{N}^{-1}$ for 25 $\mu\mathrm{m}$ wire.

III. PARAMETER DETERMINATION FOR 25 µM WIRE

We assume $D_w = 25 \, \mu \text{m}$, $D_{\text{FAB}} = 3 D_w$, substrate temperature $T = 120 \,^{\circ}\text{C}$ (glass limit) and coefficient of friction $\mu = 0.45 \, \text{[3]}$.

A. Yield Strength at 120 °C

Using (1):

$$\sigma_u(120^{\circ}\text{C}) = 88\,\text{MPa}.$$
 (6)

B. Selected Bond Force

Equation (2) yields

$$F_{\min} = 180 \,\text{mN}.$$
 (7)

A safety factor of 1.6 sets

$$F = 300 \,\mathrm{mN}. \tag{8}$$

This matches empirical practice [1].

TABLE II FINAL HB16 PROFILE AND GOVERNING RELATIONS

Setting	Value	Governing Eq./Ref.	Primary Effect
Heater T	120 °C	_	Softens Au $[\sigma_y]$
Force F	$300\mathrm{mN}$	(8)	Contact area
US Power $P_{\rm US}$	$300\mathrm{mW}$	(10)	Slip energy
US Time t	50 ms	(10)	Deformation
Tail Step	$400 \mu m$	[7]	Sets FAB size
Up CO	100 μm	[7]	Wire tear
Y-Way	50 μm	[7]	Wire tear

C. Ultrasonic Energy and Time

From (4) with F from (8):

$$E_{\min} = 14.5 \,\mathrm{mJ}.$$
 (9)

Choosing $P_{\rm US}=300\,{\rm mW}$ gives

$$t = \frac{E_{\min}}{P_{\text{US}}} = 50 \,\text{ms}. \tag{10}$$

D. Predicted Bump Diameter

Using (5) with (10) and $F = 0.3 \,\text{N}$:

$$D_m = 78 \,\mu\text{m}. \tag{11}$$

IV. EXPERIMENTAL VERIFICATION

A TPT HB16 implemented the calculated profile. Table II lists the settings.

A. Geometry Results

Measured diameter:

$$\overline{D_m} = 78.1(7) \,\mu\text{m}.$$
 (12)

V. CONCLUSION

Raising the chuck to 120 °C lowers gold yield strength, permitting reduced ultrasonic time while maintaining bond integrity. The derived expressions (2)-(5) predict optimal parameters that were confirmed experimentally.

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